



Metrics Japan TC Chapter Meeting Summary and Minutes

Japan Standards Fall 2020 Meetings
Friday, September 4, 2020, 10:00 – 12:00
SEMI Japan office, Tokyo, Japan

TC Chapter Announcements
Next TC Chapter Meeting
Date & Time: TBD

Table 1 Meeting Attendees

Italics indicate virtual participants

Chair: Mitsune Sakamoto (ZAMA Consulting)
SEMI Staff: Chie Yanagisawa (SEMI Japan)

<i>Company</i>	<i>Last</i>	<i>First</i>	<i>Company</i>	<i>Last</i>	<i>First</i>
<i>Fab Consulting</i>	<i>Bouldin</i>	<i>David</i>	Tokyo Electron	Mashiro	Supika
<i>Hitachi High-Technologies</i>	<i>Yamamoto</i>	<i>Koichi</i>	Tokyo Electron	<i>Horiguchi</i>	<i>Takahiro</i>
<i>KOKUSAI ELECTRIC</i>	<i>Matsuda</i>	<i>Mitsuhiro</i>	ZAMA Consulting	Sakamoto	Mitsune
<i>Murata Machinery</i>	<i>Tominaga</i>	<i>Tadamasa</i>	SEMI NA	<i>Sun</i>	<i>Michelle</i>
SCREEN Semiconductor Solutions	Nishimura	Takayuki	SEMI Japan	Nakajo	Mami
			SEMI Japan	Yanagisawa	Chie

Table 2 Leadership Changes

<i>WG/TF/SC/TC Name</i>	<i>Previous Leader</i>	<i>New Leader</i>
None		

Table 3 Committee Structure Changes

<i>Previous WG/TF/SC Name</i>	<i>New WG/TF/SC Name or Status Change</i>
None	

Table 4 Ballot Results

<i>Document #</i>	<i>Document Title</i>	<i>Committee Action</i>
6578	Revision to SEMI E10-0814E SPECIFICATION FOR DEFINITION AND MEASUREMENT OF EQUIPMENT RELIABILITY, AVAILABILITY, AND MAINTAINABILITY (RAM) AND UTILIZATION	Failed and returned to TF for rework
6579	Revision to SEMI E79-0814E SPECIFICATION FOR DEFINITION AND MEASUREMENT OF EQUIPMENT PRODUCTIVITY	Failed and returned to TF for rework
6599	Line-Item Revision to SEMI E180-1219,	



Table 4 Ballot Results

<i>Document #</i>	<i>Document Title</i>	<i>Committee Action</i>
	TEST METHOD FOR MEASURING SURFACE METAL CONTAMINATION THROUGH ICP-MS OF CRITICAL CHAMBER COMPONENTS USED IN SEMICONDUCTOR WAFER PROCESSING	
Line Item 1	SEMI E180 - To clarify what is discarded after the extraction solution is collected	Passed as balloted

Note 1: **Passed** ballots and line items will be submitted to the ISC Audit & Review Subcommittee for procedural review.

Note 2: **Failed** ballots and line items were returned to the originating task forces for re-work and re-balloting or abandoning.

Table 5 Activities Approved by the GCS prior to the Originating TC Chapter meeting

<i>#</i>	<i>Type</i>	<i>SC/TF/WG</i>	<i>Details</i>
None			

Table 6 Authorized Activities

Listing of all revised or new SNARF(s) approved by the Originating TC Chapter.

<i>#</i>	<i>SC/TF/WG</i>	<i>Details</i>
None		

Note 1: SNARFs and TFOFs are available for review on the SEMI Web site at:

<http://downloads.semi.org/web/wstdsbal.nsf/TFOFSNARE>

Table 7 Authorized Ballots

<i>#</i>	<i>When</i>	<i>TF</i>	<i>Details</i>
None			

Table 8 SNARF(s) Granted a One-Year Extension

<i>#</i>	<i>TF</i>	<i>Title</i>	<i>Expiration Date</i>
None			

Table 9 SNARF(s) Abolished

<i>#</i>	<i>TF</i>	<i>Title</i>
None		

Table 10 Standard(s) to receive Inactive Status

<i>Standard Designation</i>	<i>Title</i>
	*There is no published Standards originated by the Japan TC Chapter.

Table 11 New Action Items

<i>Item #</i>	<i>Assigned to</i>	<i>Details</i>
none		

Table 12 Previous Meeting Action Items

<i>Item #</i>	<i>Assigned to</i>	<i>Details</i>
20191212-01	SEMI Staff	<p>to remind SEMI HQ Standards staff for the next Regulation Subcommittee meeting that the following item should be added to the Regulations.</p> <ul style="list-style-type: none"> • GCS membership is automatically terminated if a GCS Member fails to submit votes in some certain times successive GCS voting request. <p>-> CLOSE</p>
20191212-02	Japan RF System liaison TF	<p>to prepare Ballot #6550A for submission in Cycle 4-2020</p> <p>-> OPEN</p>



1 Welcome, Reminders, and Introductions

Mitsune Sakamoto (ZAMA Consulting) called the meeting to order at 10:00. The meeting reminders on antitrust issues, intellectual property issues and holding meeting with international attendance were reviewed. Attendees introduced themselves.

Attachment: 01-02_SEMI Standards Required Elements_June2020_E+J

2 Review of Previous Meeting Minutes

The TC Chapter reviewed the minutes of the previous meeting.

Motion:	To approve the previous meeting minutes as written.
By / 2nd:	Supika Mashiro (Tokyo Electron) / Takayuki Nishimura (SCREEN Semiconductor Solutions)
Discussion:	None
Vote:	2 in favor and 0 opposed. Motion passed.

Attachment: 02-00_20191212_Metrics-Japan_MeetingMinutes_final

3 Liaison Reports

3.1 Metrics Europe TC Chapter

Chie Yanagisawa (SEMI Japan) reported for the Metrics Europe TC Chapter there is no update.

3.2 Metrics North America TC Chapter

Michelle Sun (SEMI North America) reported for the Metrics North America TC Chapter as attached.

Attachment: 03-02_NA Metrics Report Sep 2020_v2.1

3.3 SEMI Staff Report

Chie Yanagisawa (SEMI Japan) gave the SEMI Staff Report as attached. Items are:

- Staff Assignment
- SEMI Global Calendar of Events
- 2020 Critical Dates for SEMI Standards Ballots
- SEMI Standards Publications
- connect@semi
- Regulations and Procedure Manual Update

Attachment: 04-00_Staff Report August 2020_v1

4 Ballot Review

NOTE 1: TC Chapter adjudication on ballots reviewed is detailed in the Audits & Review (A&R) Subcommittee Forms for procedural review. The A&R forms are available as attachments to these minutes. The attachment number for each balloted document is provided under each ballot review section below.

The following ballot review were transferred from the NA TC Chapter to the Japan TC Chapter approved by GCS.

4.1 Document #6578: Revision to SEMI E10-0814E: “Specification for Definition and Measurement Of Equipment Reliability, Availability, And Maintainability (Ram) And Utilization”

- The ballot failed and returned to the TF for rework.

4.2 Document #6550: Revision to SEMI E113-0306 (Reapproved 0518), “Specification for Semiconductor Processing Equipment RF Power Delivery Systems” with title change to “Specification for RF Power Delivery Systems Used in Semiconductor Processing Equipment”

- The ballot failed and returned to the TF for rework.

4.3 Document #6599: Line-Item Revision to SEMI E180-1219, Test Method for Measuring Surface Metal Contamination Through ICP-MS Of Critical Chamber Components Used in Semiconductor Wafer Processing

4.3.1 Line Item 1: SEMI E180 - To clarify what is discarded after the extraction solution is collected

- passed TC Chapter review as balloted and will be forwarded to the ISC A&R SC for procedural review.

Attachment: 05-01_6578_BallotReport_v3, 05-02_6579_BallotReport_v3, 05-03_6599_BallotReport_v2

5 TF/SG Report

5.1 ESD/ESC Task Force

Chie Yanagisawa (SEMI Japan) reported for the task force that there has been no activity.

5.2 International Environmental Contamination Control (ECC) Task Force

Chie Yanagisawa (SEMI Japan) reported for the task force that there has been no activity.

5.3 Japan RF Measurement liaison Task Force

Supika Mashiro (Tokyo Electron) reported for the task force as attached material.

Attachment: 06-03_JA_RF Measurement LTF_Report_20200904

6 Old Business

The TC Chapter reviewed the following action item from the previous meeting.

Item #	Assigned to	Details
20191212-01	SEMI Staff	<p>to remind SEMI HQ Standards staff for the next Regulation Subcommittee meeting that the following item should be added to the Regulations.</p> <ul style="list-style-type: none"> • GCS membership is automatically terminated if a GCS Member fails to submit votes in some certain times successive GCS voting request. <p>-> CLOSE</p>



<i>Item #</i>	<i>Assigned to</i>	<i>Details</i>
20191212-02	Japan RF System liaison TF	to prepare Ballot #6550A for submission in Cycle 4-2020 -> OPEN

7 New Business

7.1 The Metrics Japan TC Chapter conducted a simulation of an Official Virtual TC Chapter Meeting during Ballot Review section of this meeting. The Metrics Japan TC Chapter unanimously agreed to choosing opt-in for Official Virtual TC Chapter meeting.

8 Action Item Review

8.1 Open Action Items

<i>Item #</i>	<i>Assigned to</i>	<i>Details</i>
20191212-02	Japan RF System liaison TF	to prepare Ballot #6550A for submission in Cycle 4-2020 -> OPEN

8.2 New Action Items

None

9 Next Meeting and Adjournment

The next meeting is TBD.

Having no further business, a motion was made to adjourn. Adjournment was at 12:00.



Respectfully submitted by:

Chie Yanagisawa

Manager

SEMI Japan

Phone: +81.3.3222.5863

Email: cyanagisawa@semi.org

Minutes tentatively approved by:

Mitsune Sakamoto (ZAMA Consulting), Chair	MMDD, 2020
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Table 13 Index of Available Attachments#1

<i>Title</i>	<i>Title</i>
01-02_SEMI Standards Required Elements_August2018_E+J	05-01_6578_BallotReport_v3
02-00_20191212_Metrics-Japan_MeetingMinutes_final	05-02_6579_BallotReport_v3
03-02_NA Metrics Report Sep 2020_v2.1	05-03_6599_BallotReport_v2
04-00_Staff Report August 2020_v1	06-03_JA_RF Measurement LTF_Report_20200904

#1 Due to file size and delivery issues, attachments must be downloaded separately. A .zip file containing all attachments for these minutes is available at www.semi.org. For additional information or to obtain individual attachments, please contact Chie Yanagisawa at the contact information above.